

# **HERA LPOL2 laser system and polarization control**

# Introduction

The Compton cross-section averaged over scattered particles spins:

Differential cross-section

Transverse laser polarisation: nuisance parameter to minimize and keep under control

$$\frac{d\sigma}{dyd\varphi_{obs}}(x, y) = \frac{d\sigma_0}{dy}(x, y) + \frac{d\sigma_{\perp}}{dy}(x, y) \cos(2(\varphi_{obs} - \varphi_{las})) \mathcal{P}_{lin}^{las} + \frac{d\sigma_{\parallel}}{dy}(x, y) \mathcal{P}_{circ}^{las} (\mathbf{P}_T f_T(x, y) \cos(\varphi_{obs} - \varphi_{elec}) + \mathbf{P}_L f_L(x, y))$$

*Electron beam polarization independent*
*Electron beam polarization dependent*

$\mathcal{P}_{circ}^{las}$  and  $\mathcal{P}_{lin}^{las}$  = degree of linear and circular polarization of the laser beam

If one wants to determine  $\mathbf{P}_L$  and  $\mathbf{P}_T$  at the permille level, then it must be the same for laser beam polarization

## Outlook

- (some) Basic & robust laser beam polarimetric setups used in the past
  - SLD (see M. Woods) & Jlab laser cavity setup (1999, N Falletto PhD.)
  - Hera lpol cavity setup 2004
  - Precision & Limit of the method
- Improvement for higher precision

# JLAB(1999) polarimeter & SLD polarimeter

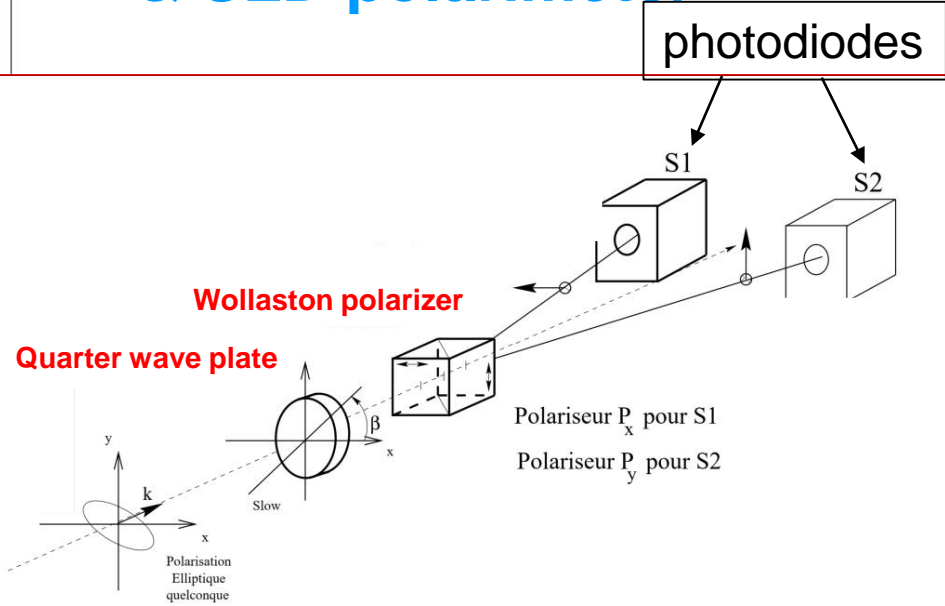
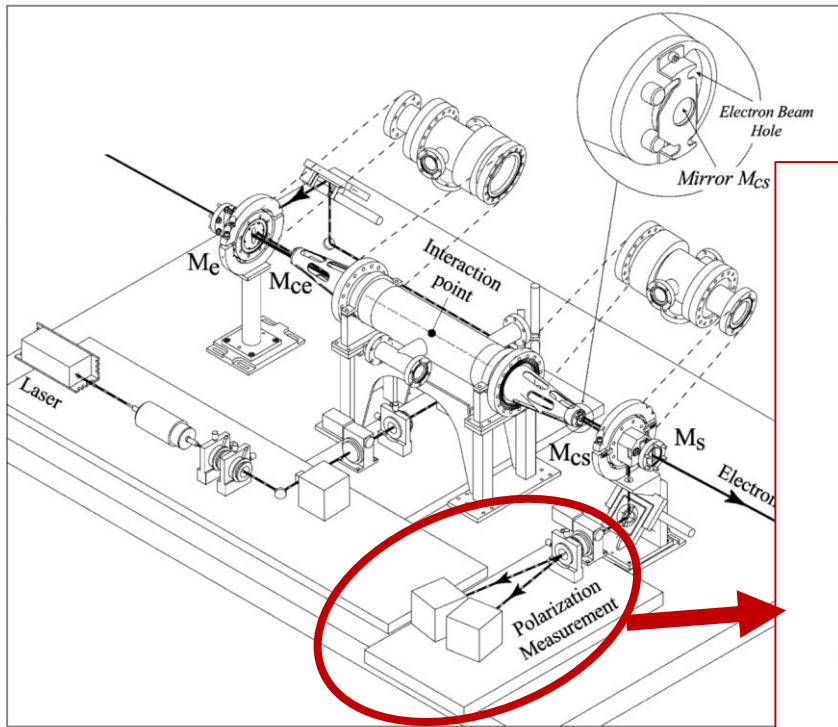


FIG. 4.12 - *Mesure de la polarisation sur le montage de TJNAF.*

**Quarter wave plate : uniaxial quartz plate with optical axis in the plane of interface ( $\beta$  angle)**  
**Thickness :**

Laser beam wavelength  $\sim 1\mu\text{m}$

$$e = \frac{\lambda}{4\Delta n} (4k + 1), k = 0, \frac{1}{2}, 1, \dots$$

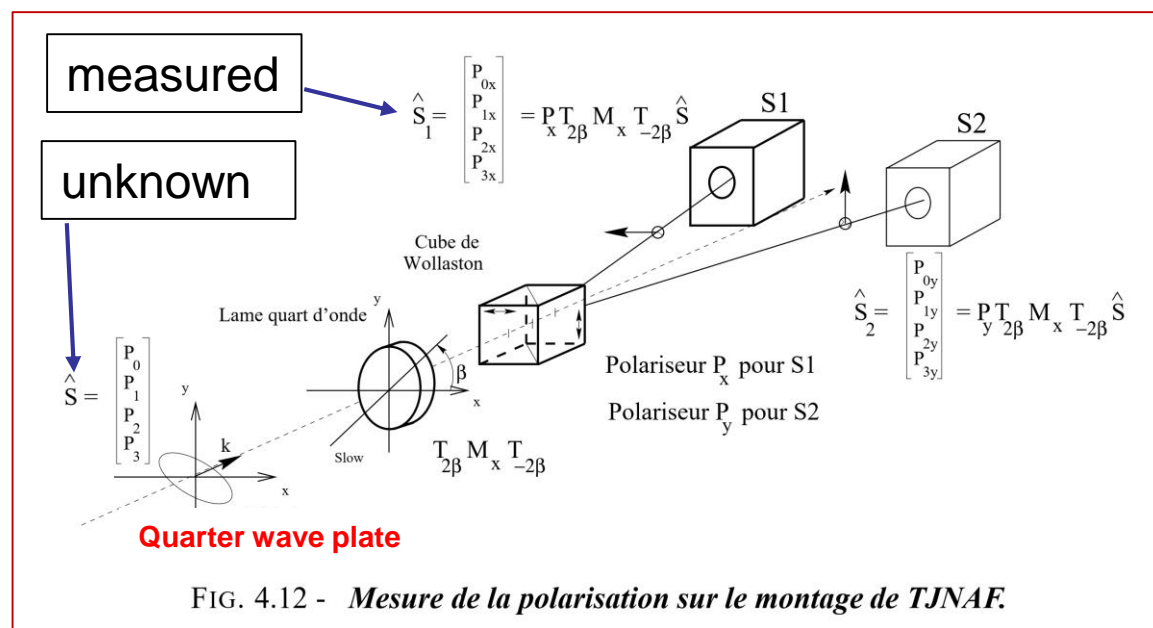
‘zero order plate’ :  
 $k=0 \rightarrow e \sim 30\mu\text{m}$   
 ‘few order’,  $k=1/2$   
 $e \sim 90\mu\text{m}$

**Wollaston polarizer: extinction  $\sim 10^{-5}$**

Birefringence  $\sim 10^{-2}$  for quartz

Assume the electric field of laser beam described by a plane wave :

Jones (Field components) formalism or Mueller (intensity components) formalism can be used (see M. Woods yesterday)



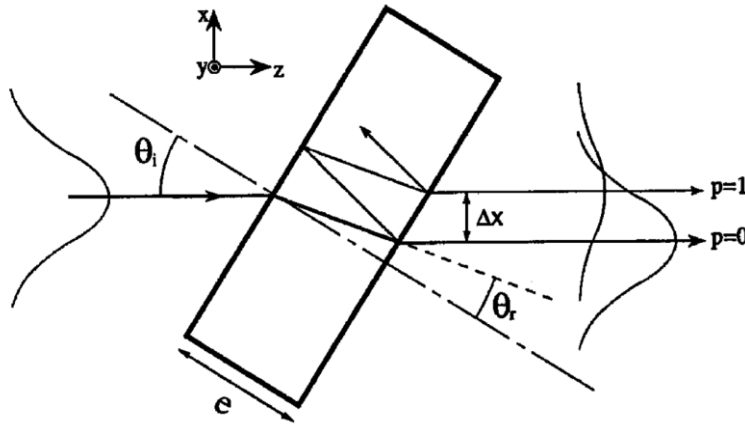
For 'perfect' QWP and polarizer :

$$P_{x/y} = \begin{pmatrix} 1 & 1/-1 & 0 & 0 \\ 1/-1 & 1 & 0 & 0 \\ 0 & 0 & 0 & 0 \\ 0 & 0 & 0 & 0 \end{pmatrix}, \quad T_{2\beta} = \begin{pmatrix} 1 & 0 & 0 & 0 \\ 0 & \cos(2\beta) & -\sin(2\beta) & 0 \\ 0 & \sin(2\beta) & \cos(2\beta) & 0 \\ 0 & 0 & 0 & 1 \end{pmatrix}$$

$$M_x = \begin{pmatrix} 1 & 0 & 0 & 0 \\ 0 & 1 & 0 & 0 \\ 0 & 0 & 0 & 1 \\ 0 & 0 & -1 & 0 \end{pmatrix}$$

The laser beam polarization is measured by rotating ( $\beta$  angle) the QWP and fitting the intensity profiles S1, S2 after the polarizer using Mueller (or Jones) matrix .

However : multiple reflexions inside quartz plate are neglected in this model



[Paraxial Gaussian beam  
Amplitude accounted for large tilts  
→ modified Jones & Mueller matrix]

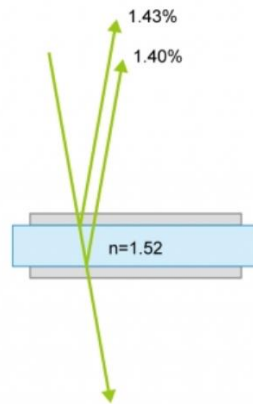
This is usually justified by using anti-reflexion coatings

Without AR coating



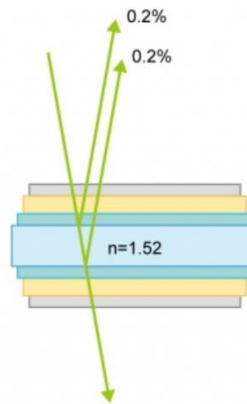
Transmittance = 91.83%  
Reflectance = 8.17%

Single-layer coating  
of  $MgF_2$



Transmittance = 97.19%  
Reflectance = 2.81%

Multi-layer coating  
by NIDEK

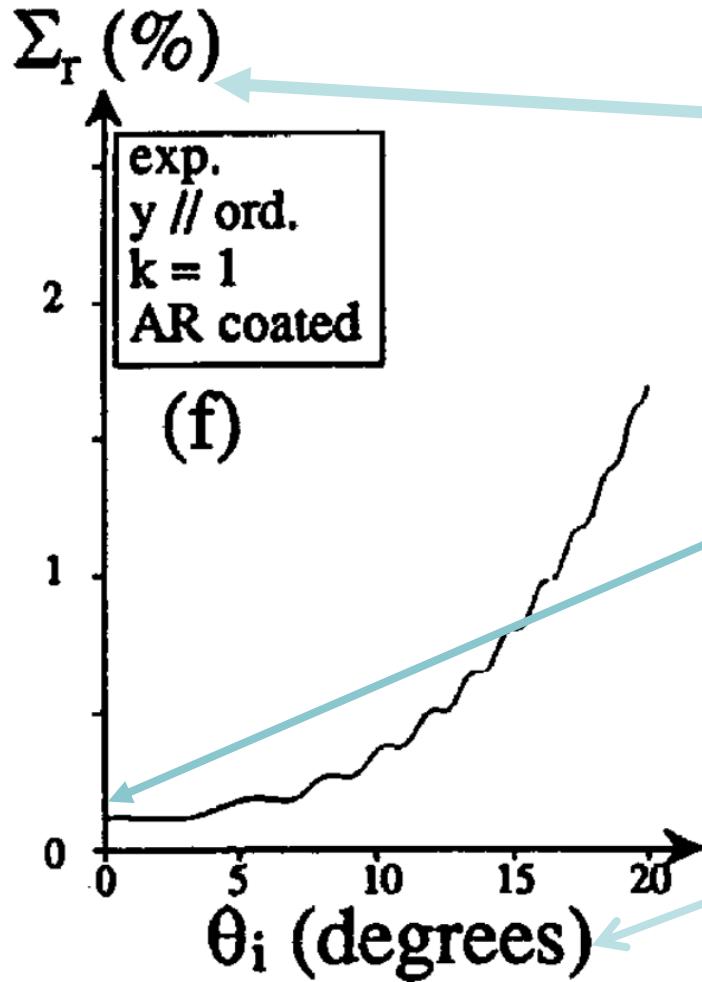


Transmittance = 99.6%  
Reflectance = 0.4%

(usually 0.2%-0.4%  
residual reflectance)

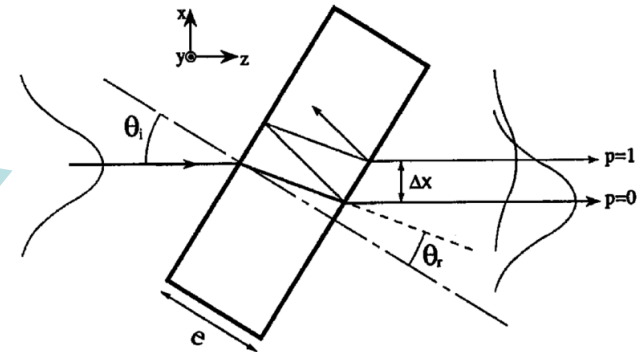
Complex system to model  
(thicknesses, optical indices...)

# Residual effect of AR coating



Residual wrong polarization vs QWP tilt angle  
 $\Sigma_r$  should be 0 at  $\theta_i=0$

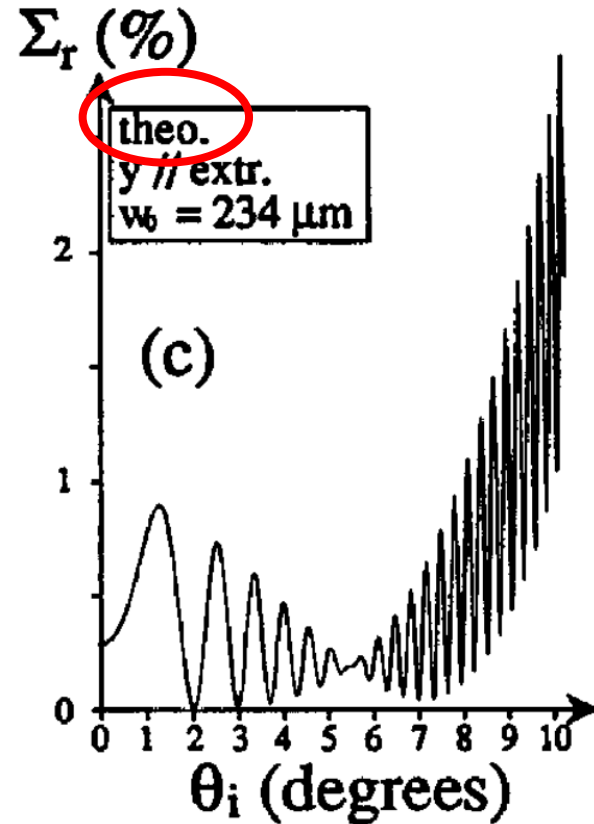
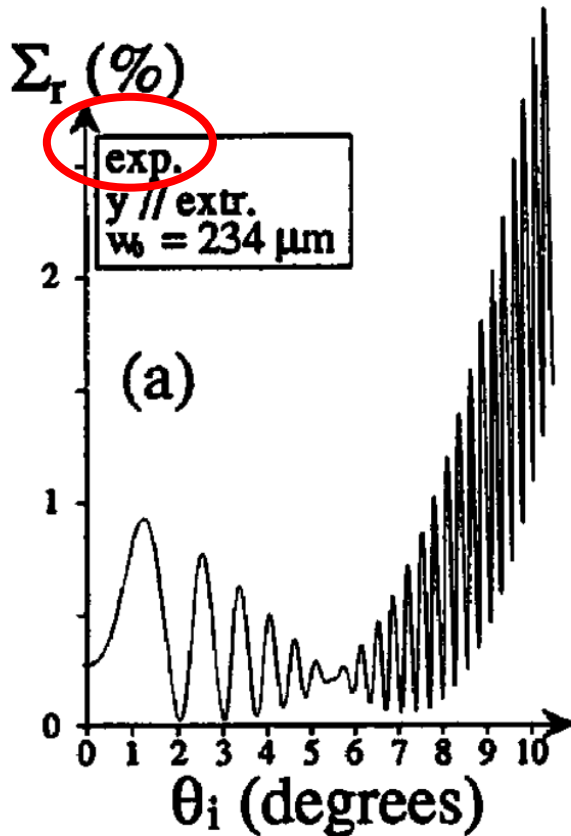
About 0.1 percent contribution from wrong polarization  
 → This gives a precision estimate on the model assumption



Precision strongly related to AR coating performance & quartz thickness

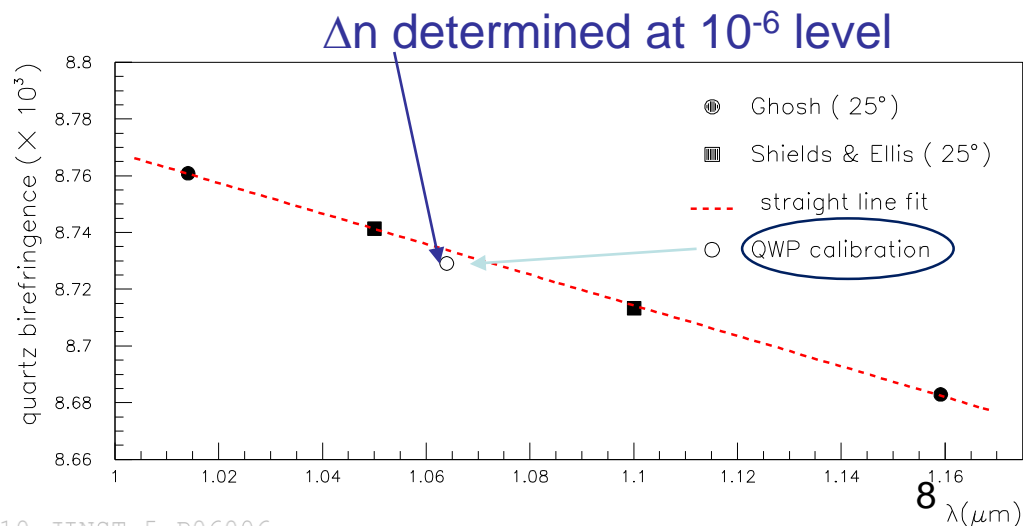
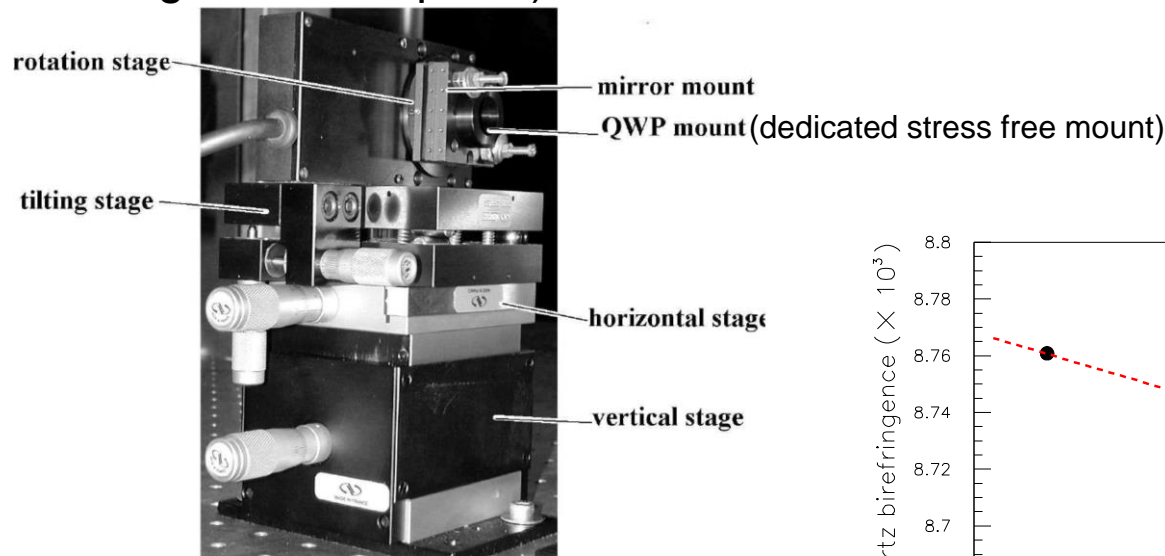
While simple uncoated plate are well modeled

QWP thickness ( $\sim 1\text{mm}$ ) corrected by  $\sim -7\%$  @  $0.01\%$  ( $\sim \lambda/500$ ) precision...

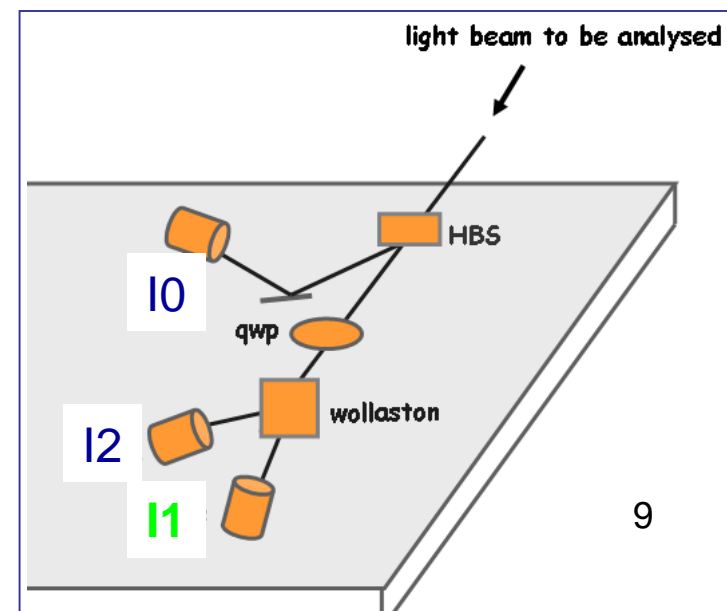
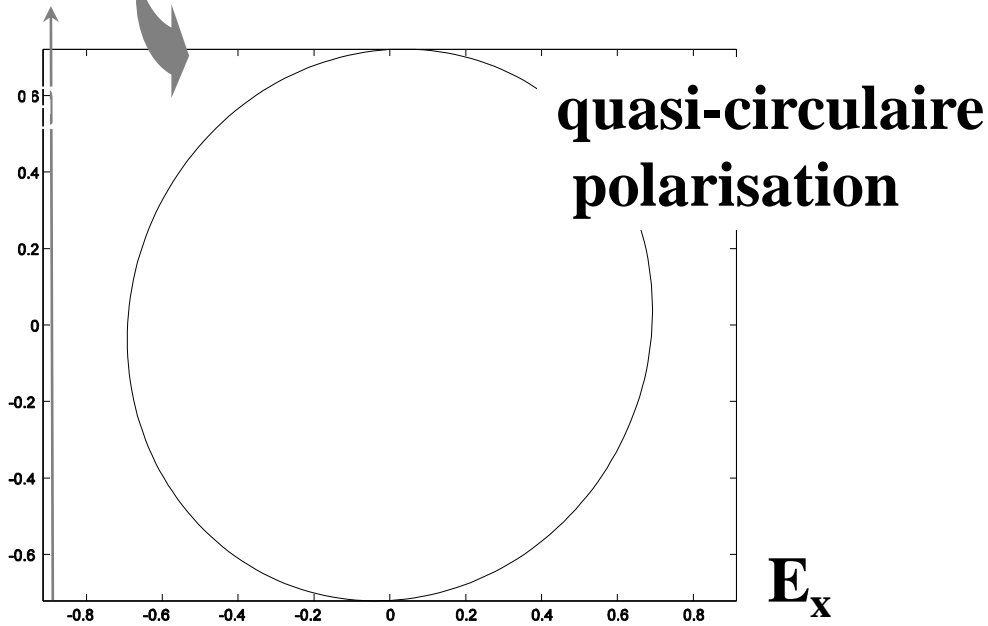
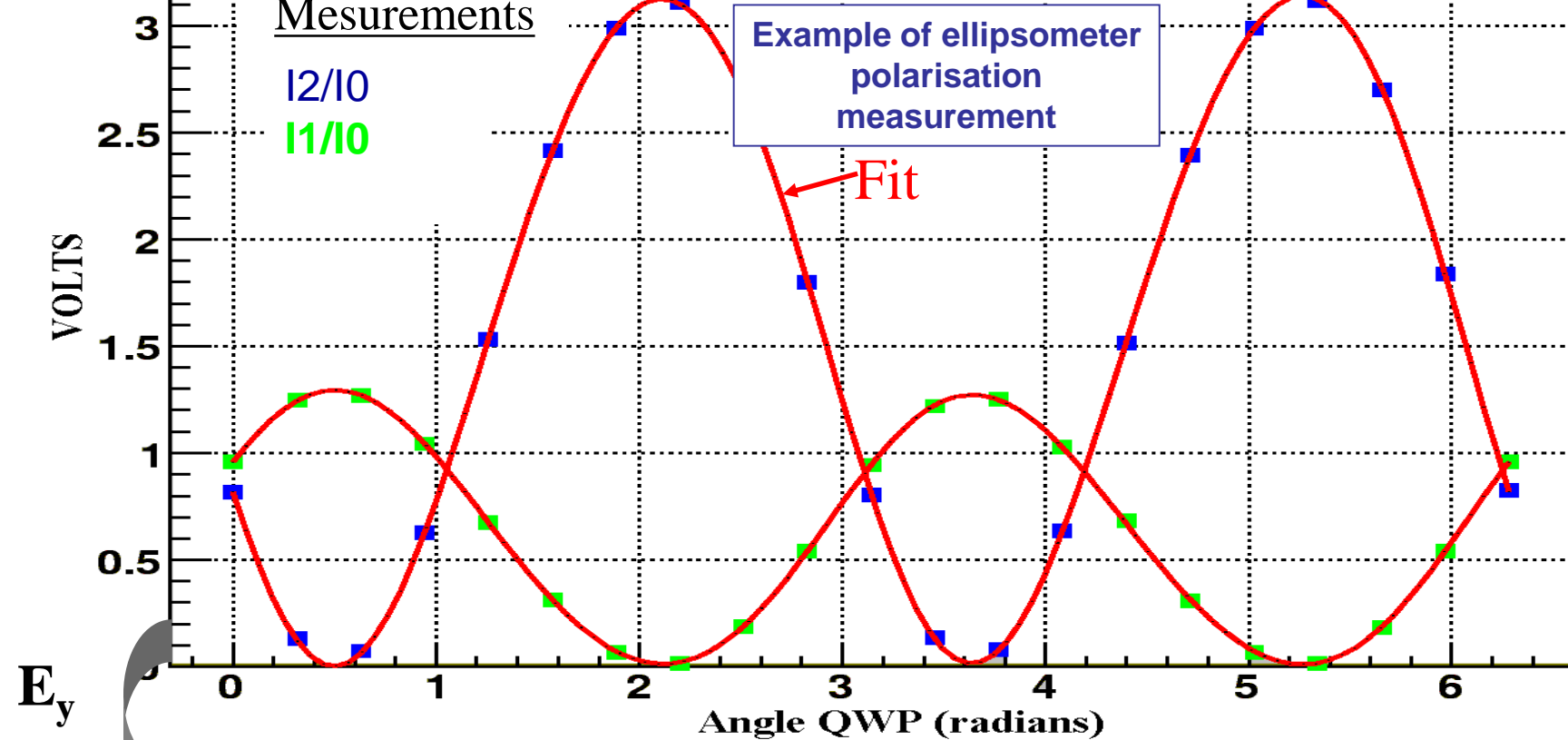


# Hera cavity polarimeter: goal 0.1% precision

- We had had bad experience with various AR coated QWP (and little funding...)
- ➔ Same laser beam polarimeter as SLD&Jlab but with an uncoated quartz plate ( $e \sim 90\mu\text{m}$ )
- Calibration by tilting and rotating 2 uncoated quartz plates (of different thicknesses)
  - Fit parameters : thickness, various misalignments parameters, birefringence  $\Delta n$  as a control parameter
- Final precision : few per mille (limited by photodiode readout stability, easy to upgrade using lock-in amplifier)





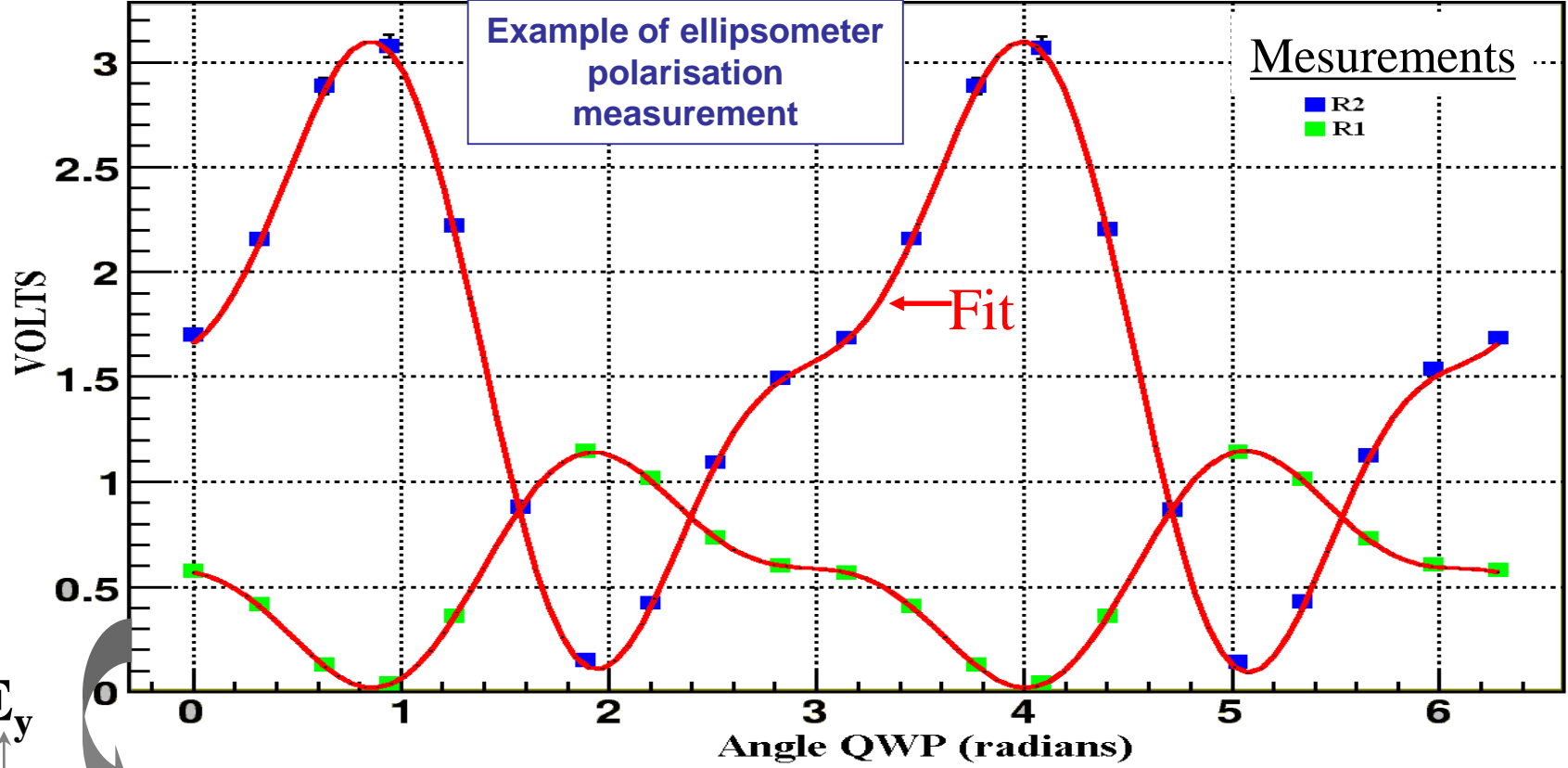


Example of ellipsometer polarisation measurement

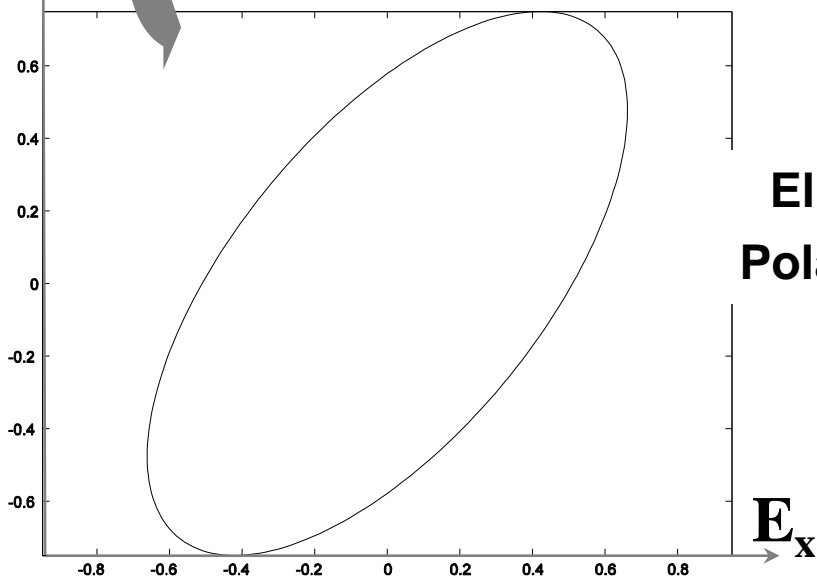
Mesurements

R2  
R1

Fit



$E_y$



Elliptical Polarisation

## Advantages of QWP+polarizer ellipsometer:

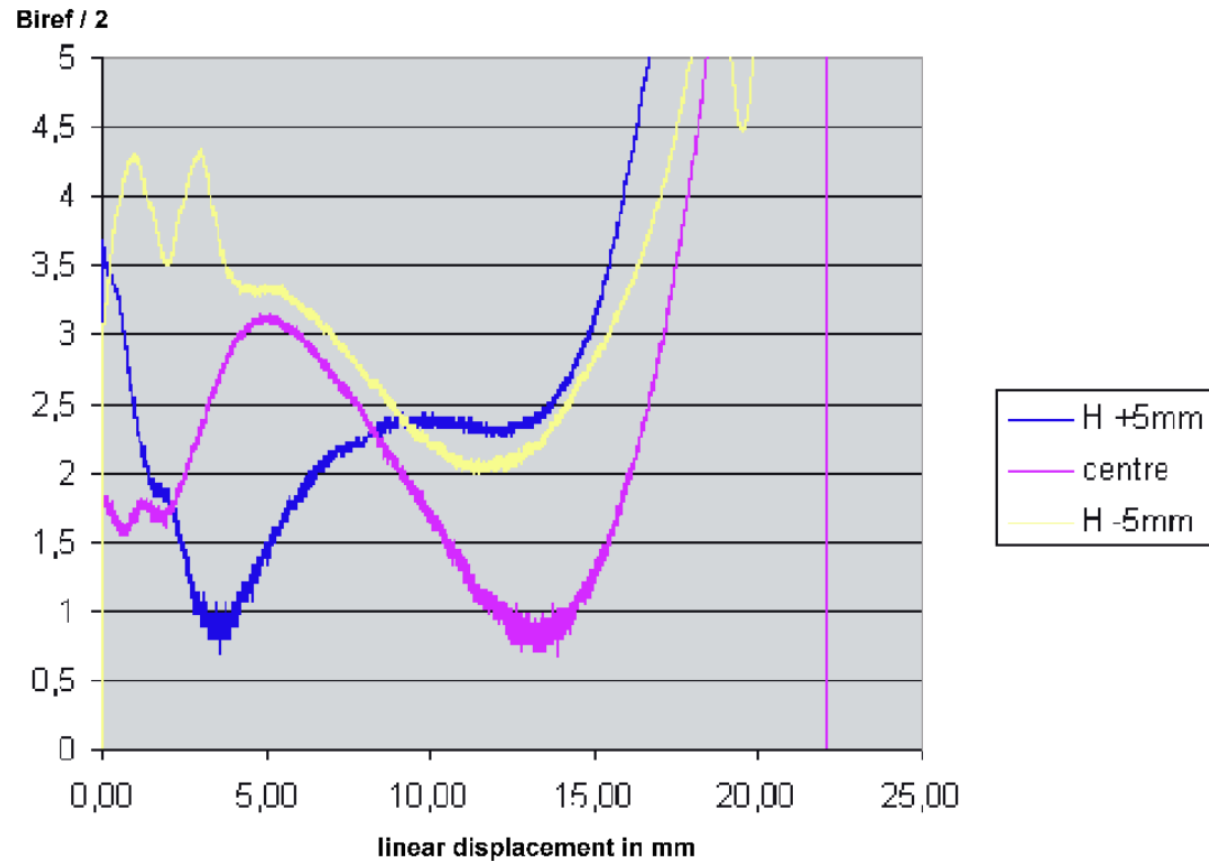
- Simple and robust method
- With some model extension e.g. :
  - For 'high' laser power :Thermoelastic induced birefringence
  - quartz optical activity or circular birefringence (induced by magnetic dipolar & quadrupolar electric responses of the crystal)  $\sim 7 \cdot 10^{-5}$  effect (though sapphire Xtal could be used)
- → at least  $10^{-4}$ - $10^{-5}$  precision should be achievable
  - Above  $10^{-5}$ , crystal homogeneity, roughness, polarizer extinction for ex. may limit the model completeness (to be studied)

## Disadvantages

- Tedious alignments
- Long time calibration
- Long time measurements

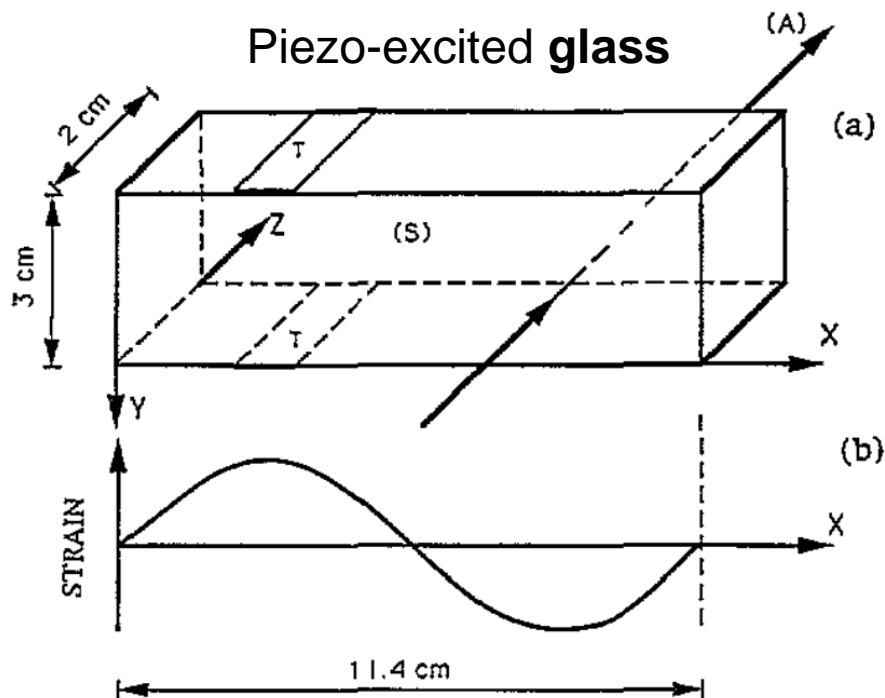
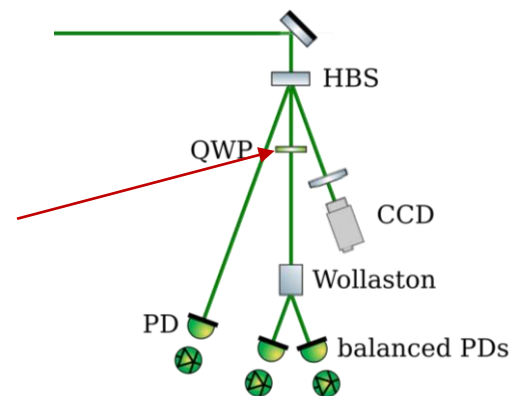
## Another limit comes from the vacuum windows

Measured birefringence (in mrad) of Lpolcav vacuum window (glass-metal welding), pollution of degree of circular polarization is in  $\text{biref}^2/2 \rightarrow 10^{-5}$  effect



# Improvement : Photo-elastic modulator

Replace motorized QWP by PEM



Birefringence induced by stress

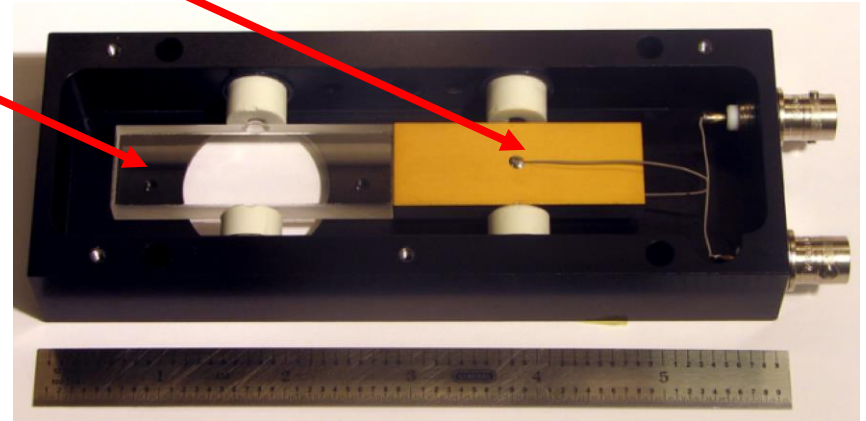
$$n_x \# n_0 \left[ 1 - \frac{n_0^2}{2} (p_{11} U_{xx} + p_{12} (U_{yy} + U_{zz})) \right]$$

$$n_y \# n_0 \left[ 1 - \frac{n_0^2}{2} (p_{12} (U_{xx} + U_{zz}) + p_{11} U_{yy}) \right] \quad (2)$$

Modulated difference of refraction indices

Modulation of phase of waveplate

- Modulation frequency : 50 kHz
  - FFT → amplitudes at various signal harmonics
    - Gives the degree of circular polarization
  - Fast and compact measurement based on ‘simple’ component: glass plate & piezo



- Parasitic effects well studied/documentated:
  - Thermal effects → feedback technics on the piezo controller
  - Anharmonicity effect → accounted in signal analysis

- Internal multiple reflexions

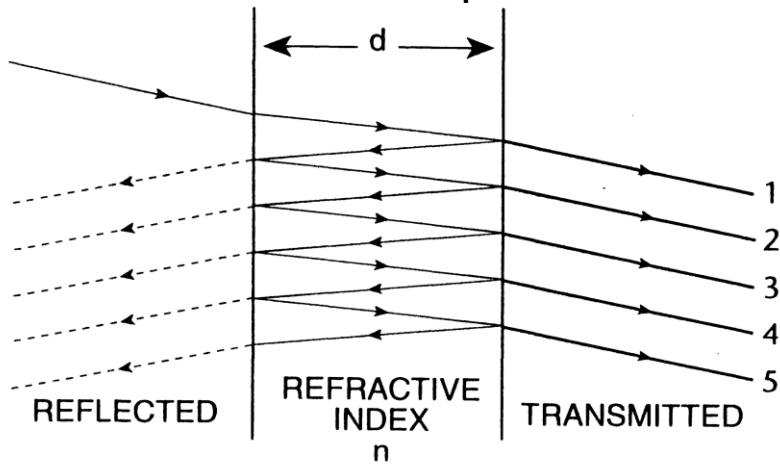
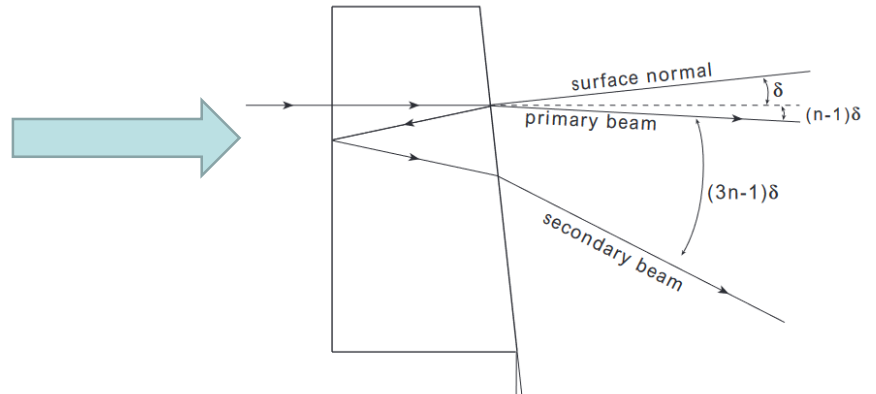
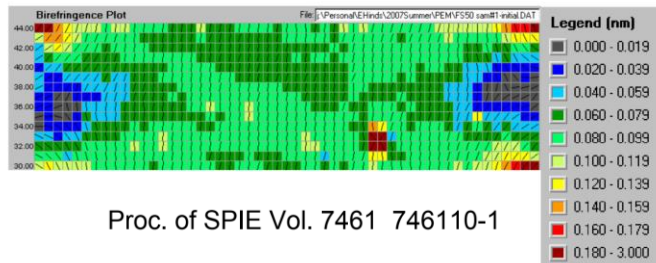
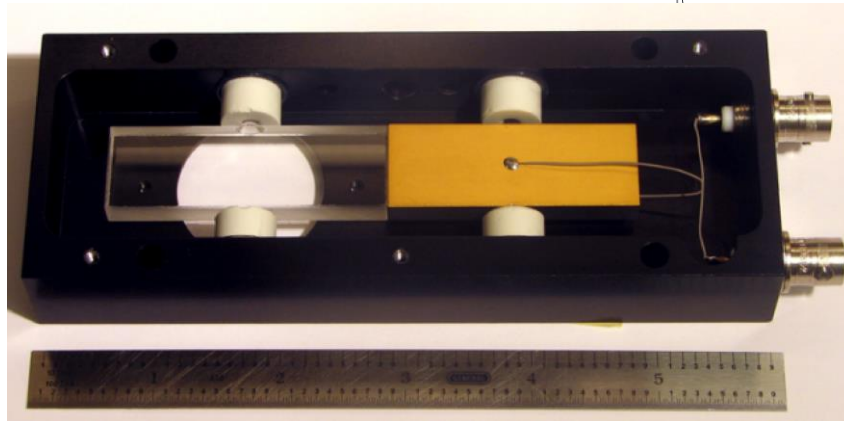


Figure 2: Interference in a PEM Optical Element

PEM wedge shape  
(Hinds Instr)



- Static birefringence
  - Extracted from signal analysis



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Fig.2. The birefringence map of a bare optical element made of fused silica, showing residual linear birefringence typically below 0.1 nm.

# Summary

- QWP+polarizer, robust ellipsometer
  - From SLD/Jlab/HERA experiences  $\sim 10^{-3}$  precision on laser beam polarization ‘easily’ attainable
  - Pushing to  $10^{-5}$  may require further ‘R&D’
  - Tedious alignment & calibration procedures (hard to automate)
- Use of PEM instead of the QWP
  - A priori:
    - Automate calibration should be possible
    - R&D needed to set precision limits
      - Already started at Orsay (A. Martens)